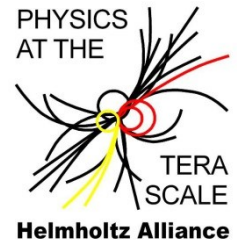




Universität Hamburg

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# Light absorption and charge collection of highly irradiated silicon sensors

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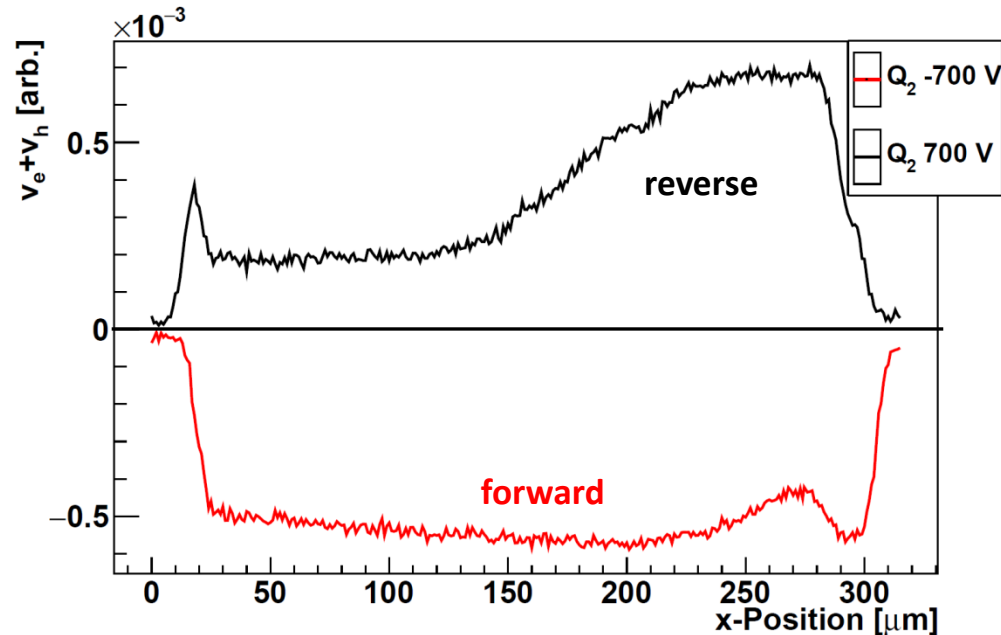
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# Motivation

$$\sum v_{e,h} \propto E$$



Strip sensor  
 285  $\mu\text{m}$  n-type  $\text{Si}$   
 $7.25 \times 10^{15} / \text{cm}^2$   
 $-30^\circ \text{C}$

## Reverse bias:

- Trapped charge carriers inhomogeneous create space charge
- Hard to extract  $E(x)$ ,  $v_{e,h}(\Phi)$ ,  $\tau_{e,h}(\Phi)$

**Forward bias:**  $v_{e,h} \approx \text{const} \rightarrow E \approx \text{const} \ \& \ \tau_{e,h} \approx \text{const}$

- Similar to low field region for reverse bias

$\rightarrow$  use charge collection length  $Q(x) = Q_0 e^{-x/\lambda_{e,h}}$  with  $\lambda_{e,h} = v_{e,h} \cdot \tau_{e,h}$

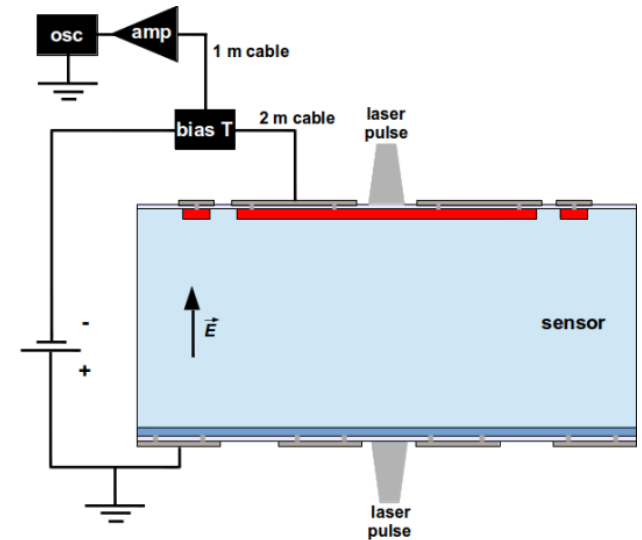
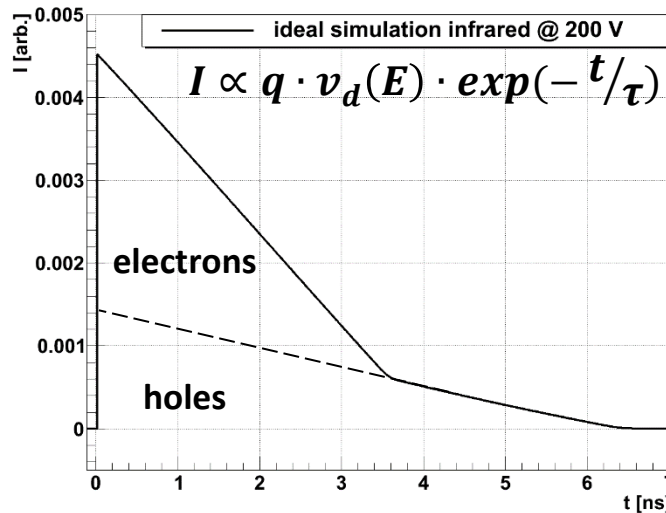
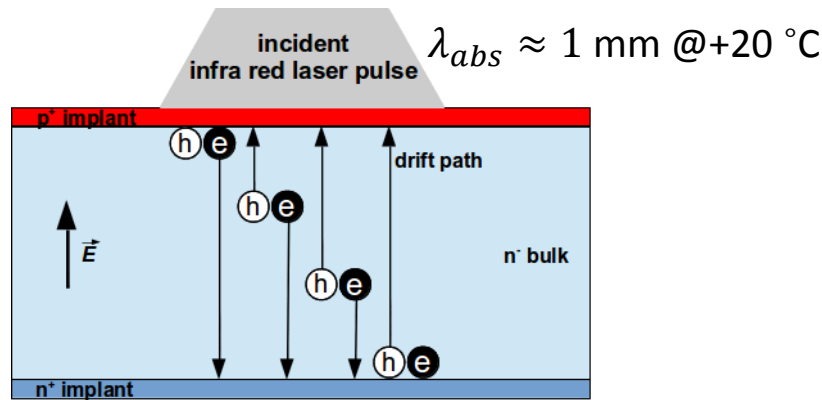
**Absorption length needed to determine  $Q_0(\alpha)$ !**



# Experimental method

# Transient Current Technique

- Infrared laser 1063 nm  
 → simultaneous **e** and **h** drift

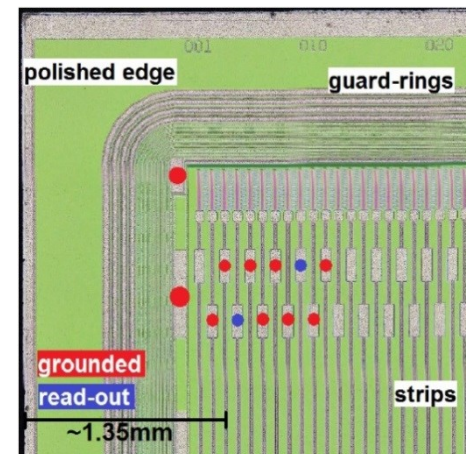
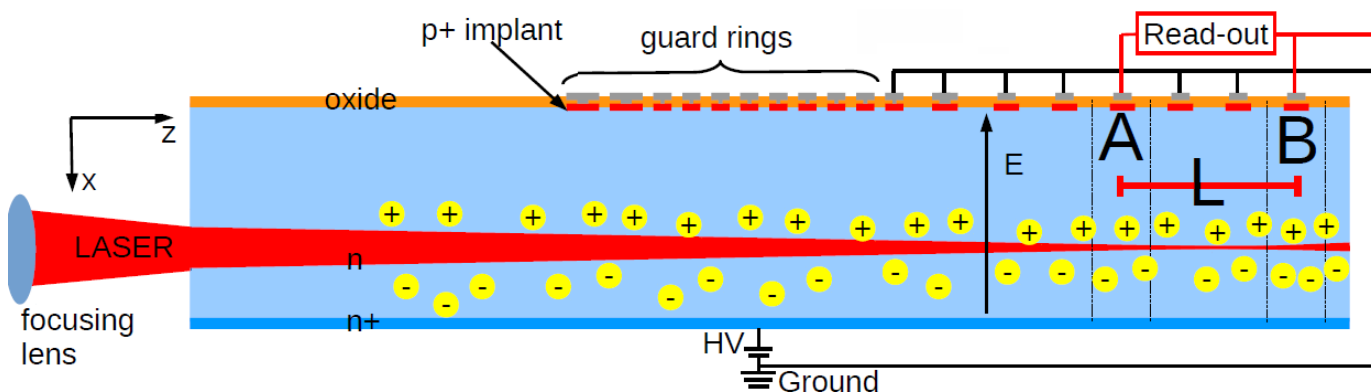


drift simulation  
 200  $\mu\text{m}$  pad diode  
 @ 200 V

# Edge Transient Current Technique

- **Infrared laser** 1052 nm  
→ signal induced by drift of **e** and **h**

$$\lambda_{abs} \approx 0.7 \text{ mm @ } +20 \text{ } ^\circ\text{C}$$



→ F. Feindt Master thesis [DESY-THESIS-2017-006]

- **Edge illumination of strip sensors**  
→ charge carriers created at defined depth in the sensor
- **Two read-out channels**  
→ absorption can be measured between two strips

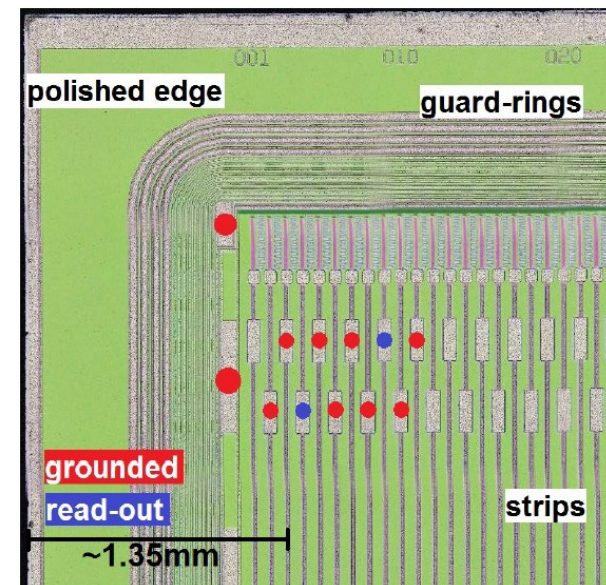
Weighting field is assumed constant

Distortion of the electric field near the strips not accounted for

# Investigated structures

Investigated structures irradiated to  $9E14 - 1.3E16 n_{eq}/cm^2$

- Bare silicon wafers (not processed)
- Diodes
  - Initial doping  $N_D = (8E11 - 4E12) /cm^3$
  - Hamamatsu, float-zone: n- and p-type, 200  $\mu m$ , area 5 mm<sup>2</sup> & 25 mm<sup>2</sup>
  - Hamamatsu, Magnetic Czochralski: p-type, 200  $\mu m$ , area 5 mm<sup>2</sup> & 25 mm<sup>2</sup>
  - CiS, float-zone, n-type, 285  $\mu m$ , 25 mm<sup>2</sup>
- Strip sensors
  - CiS, float-zone, n-type, 285  $\mu m$ ,  $N_D = 8E11 /cm^3$ 
    - Pitch 80  $\mu m$
    - Implant 18  $\mu m$
    - Aluminum 16  $\mu m$

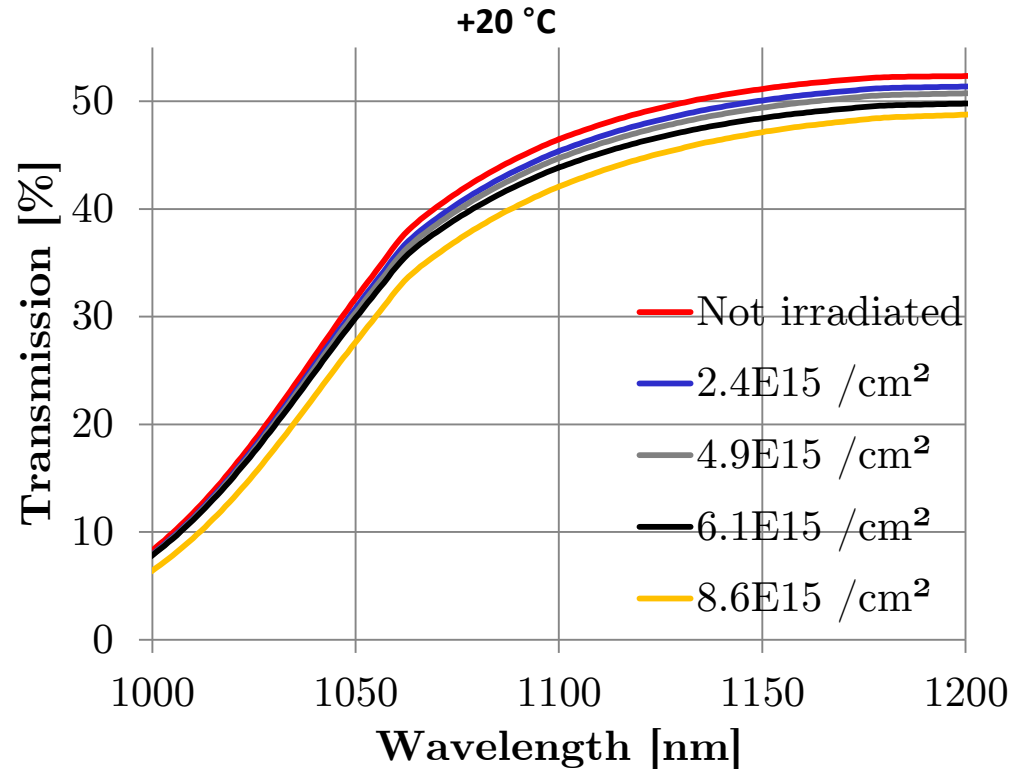
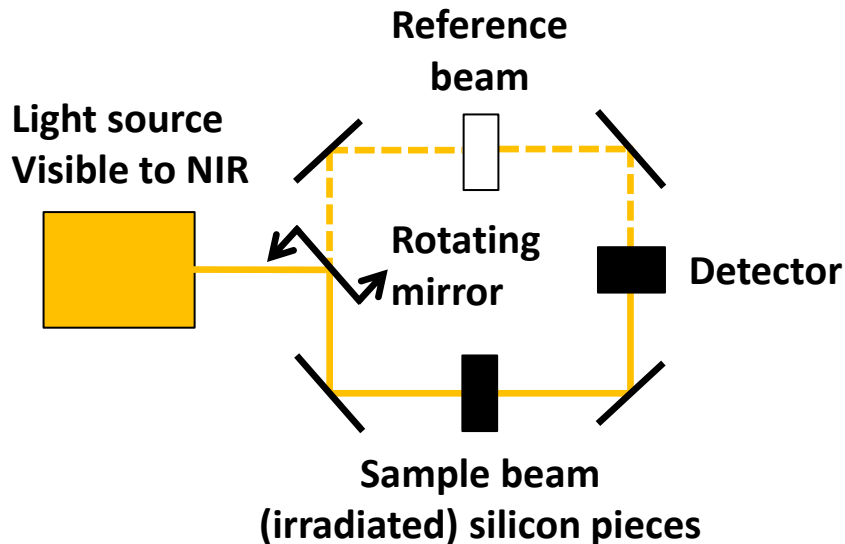




# Results

# Absorption of light in irradiated silicon

## Spectrophotometer

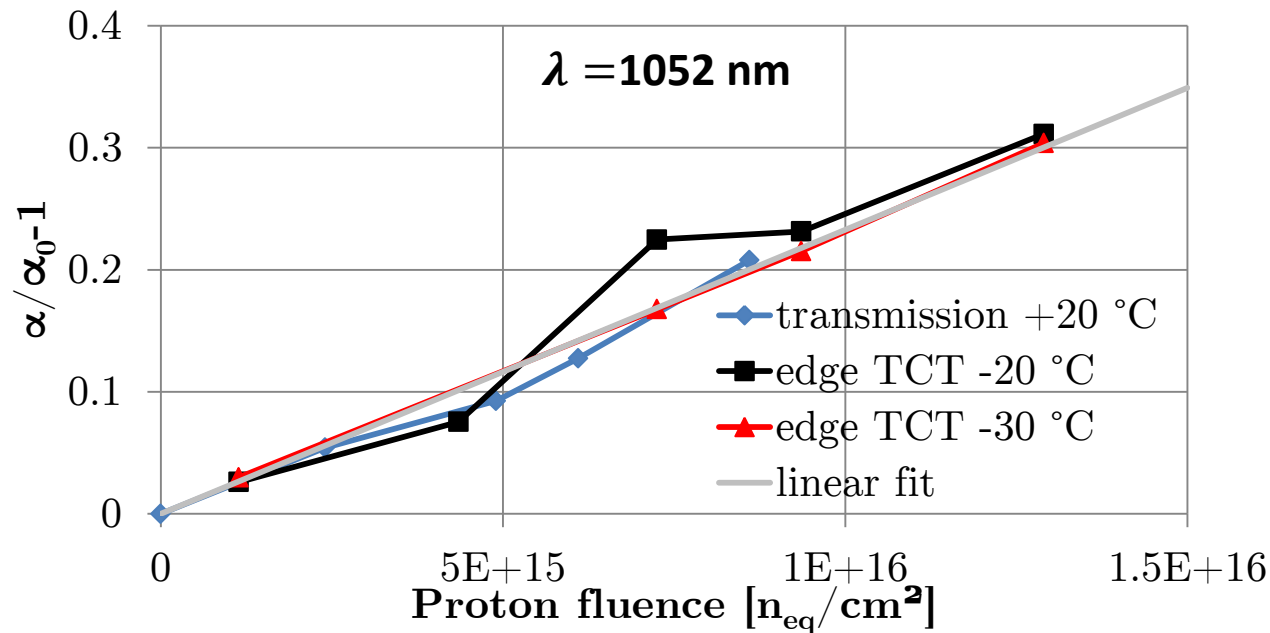


NIR light transmission measured for wide range of wavelengths

- Absorption increases @ RT and without bias voltage**  
 → compare results w/ edge-TCT measurements w/ bias voltage @ low  $T$



# Absorption of light in irradiated silicon



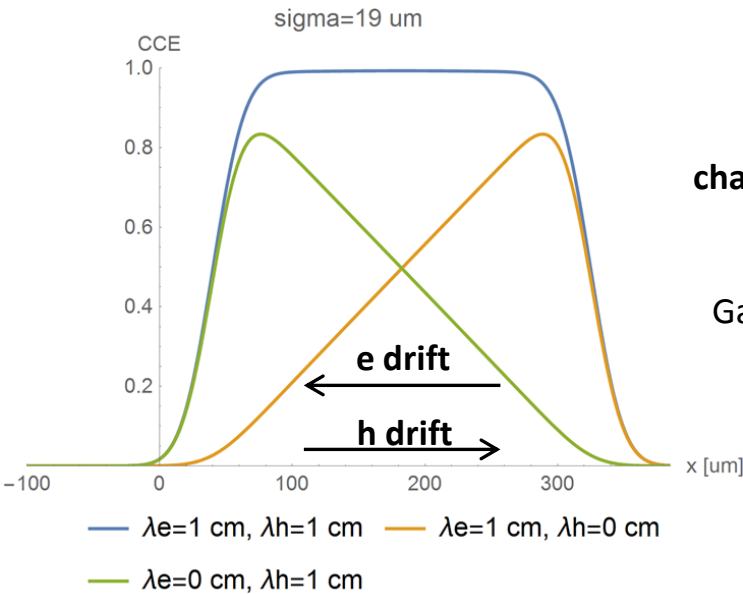
Absorption coefficient  $\alpha \propto n_{abs}(\Phi) \rightarrow \text{Plot } \frac{\alpha(\Phi, T)}{\alpha_0(T)} - 1 \text{ vs. } \Phi$

- $T$  dependence for damage induced absorption = interband absorption**

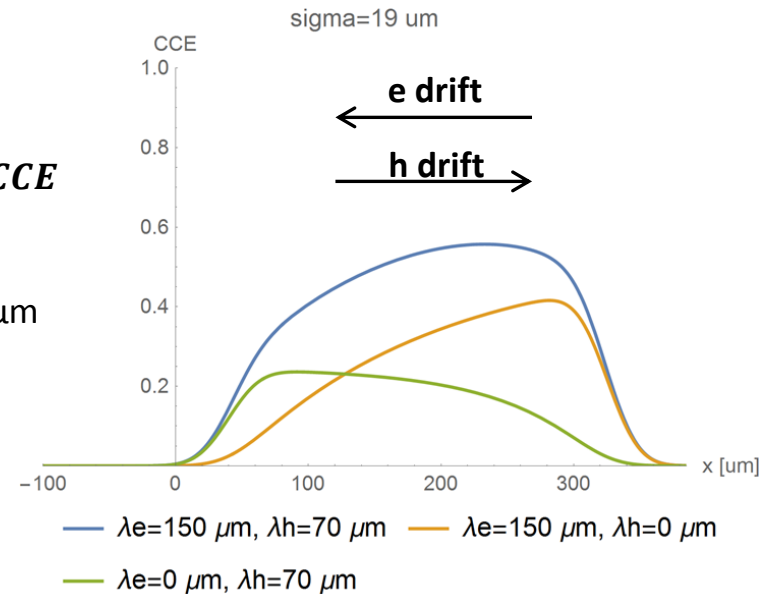
$$\rightarrow \alpha(\Phi, \lambda, T) = \alpha_0(\lambda, T) \cdot \left( 1 + \frac{\Phi}{\Phi_{abs}(\lambda)} \right)$$

$$\begin{aligned} \Phi_{abs}(1052 \text{ nm}) &= 4.30\text{E}16 / \text{cm}^2 \\ \Phi_{abs}(1064 \text{ nm}) &= 3.32\text{E}16 / \text{cm}^2 \end{aligned}$$

# Edge TCT charge profile



charge collection efficiency  $CCE$   
 vs. laser position  $x$   
 of a 285  $\mu\text{m}$  sensor w/  
 Gaussian laser beam  $\sigma=19 \mu\text{m}$

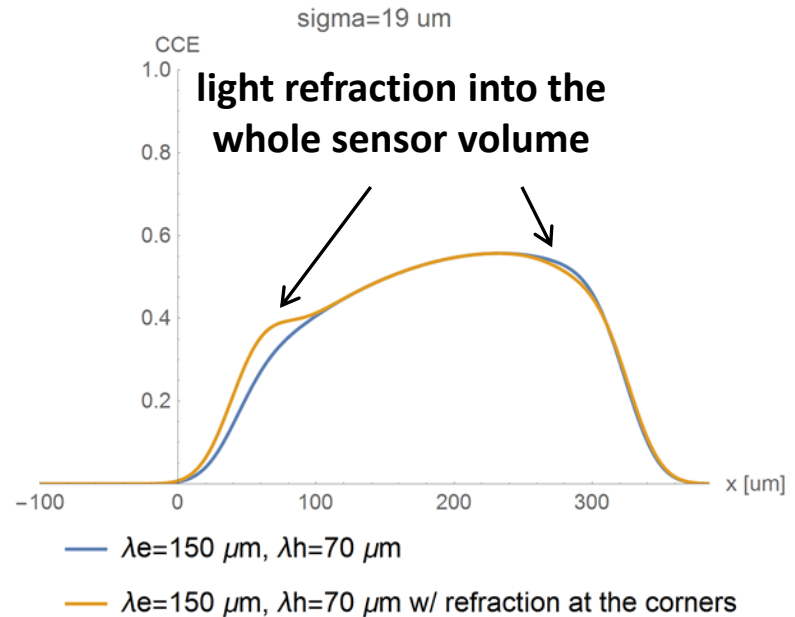
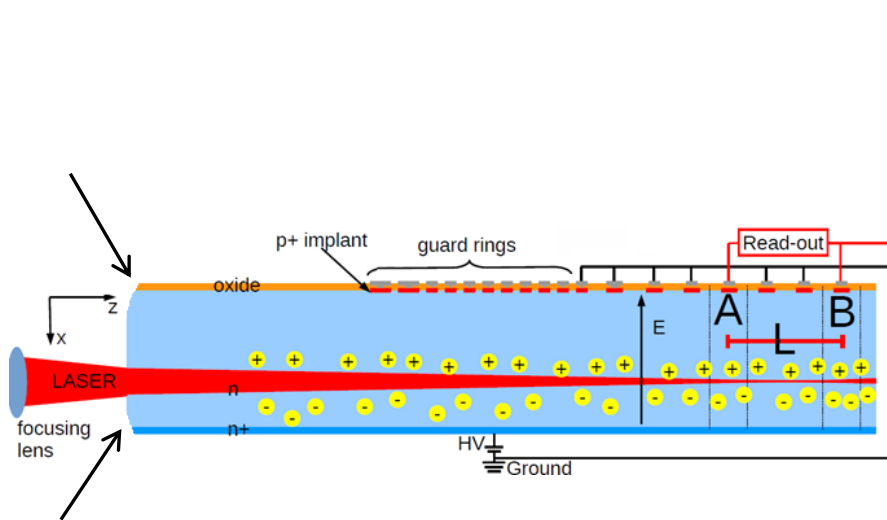


Use edge-TCT charge profile to determine charge collection length  $\lambda_{e,h}$

- Assume  $E(x) = \text{const}$  and  $\tau_{e,h} = \text{const}$

$$Q(x) = q \cdot \frac{\int_0^d \left( \int_{x_0}^d e^{-\frac{(x_0-x)^2}{2\sigma^2}} \cdot e^{-\frac{x-x_0}{\lambda_{ccl}^e}} dx \right) dx_0 + \int_0^d \left( \int_0^{x_0} e^{-\frac{(x_0-x)^2}{2\sigma^2}} \cdot e^{-\frac{x_0-x}{\lambda_{ccl}^h}} dx \right) dx_0}{d\sigma\sqrt{2\pi}} \quad (5.12)$$

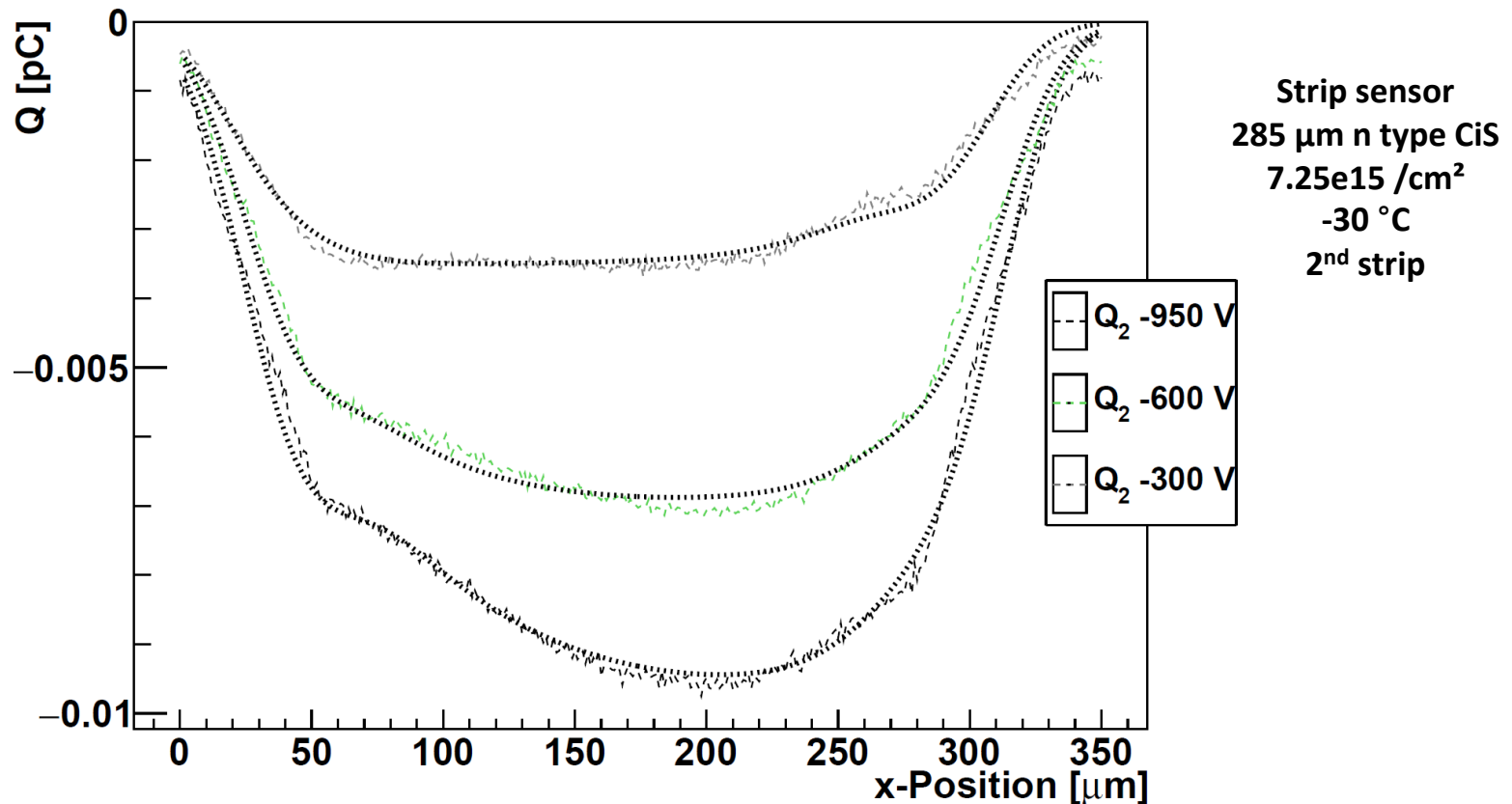
# Edge TCT charge profile



Rounding of the edge & reflections modify the initial charge distribution (also affects the velocity profile)

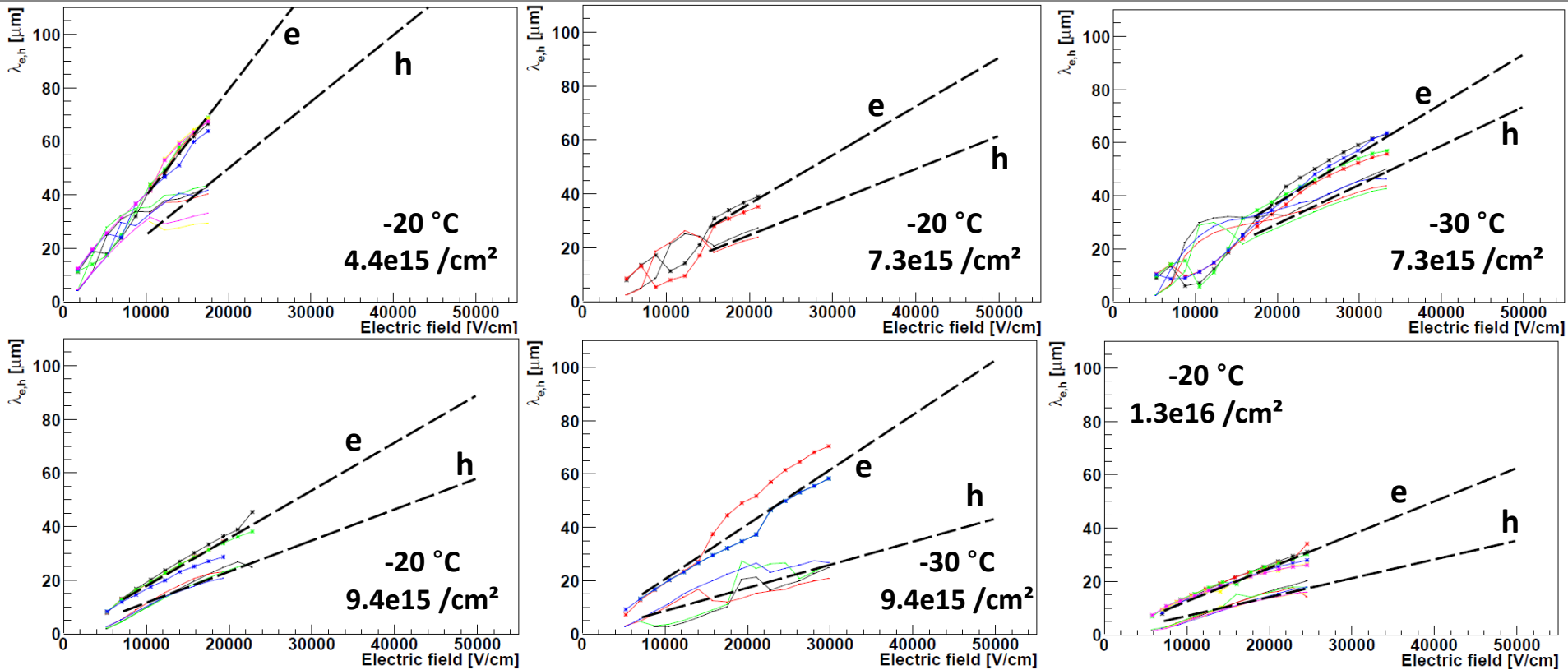
- Use superposition of two Gaussian beams (wide & narrow) near edges  
 → fit  $\lambda_{e,h}$  to measurements

# Fit of the charge profile



- Obtaining  $\lambda_{e,h}$  by fitting the  $CCE(x)$  seems to work  
→ measurements + analysis ongoing for -20 °C and -30 °C @ fluences 4.4E15 – 1.3E16 /cm<sup>2</sup> and for both read out strips

# The charge collection length

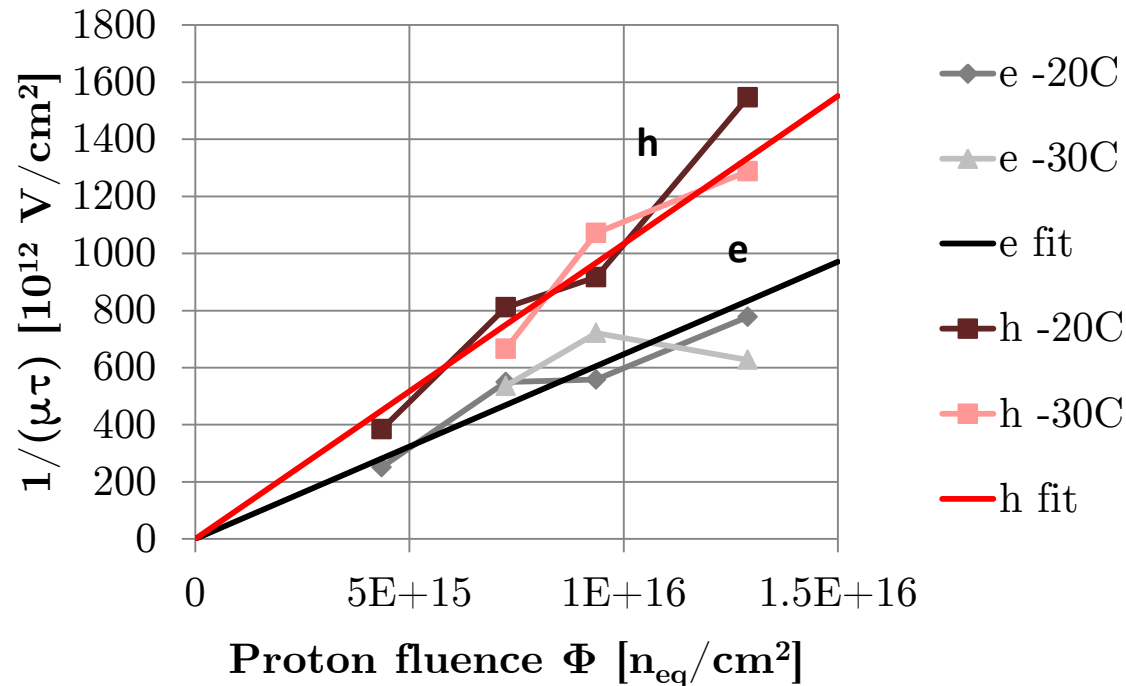


Charge collection length  $\lambda_{e,h} \propto 1/n_{trap}$

- $\lambda_{e,h}(E) = v(E)\tau = \mu\tau \cdot E \approx const \cdot E$

→  $E$  dependence of  $\mu(E)$  and  $\tau(E)$  seem to cancel in the investigated region

# The charge collection length



Charge collection length  $\lambda_{e,h} \propto 1/n_{trap}$

- $\lambda_{e,h}(E) = v(E)\tau = \mu\tau \cdot E$
- Assume  $\frac{1}{\mu\tau}(\Phi) = c_{ccl} \cdot \Phi$

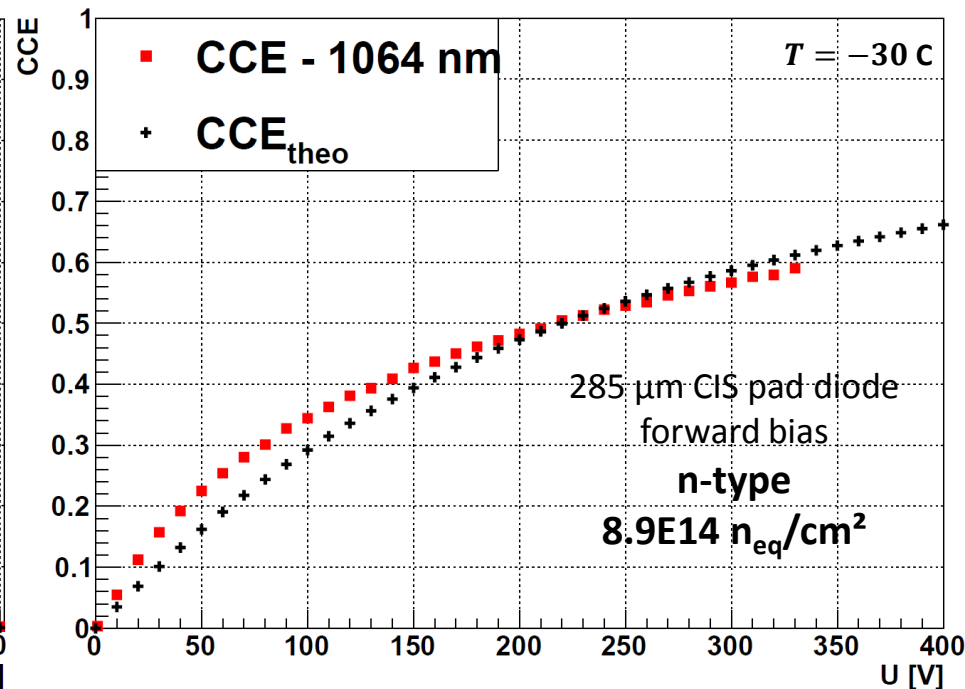
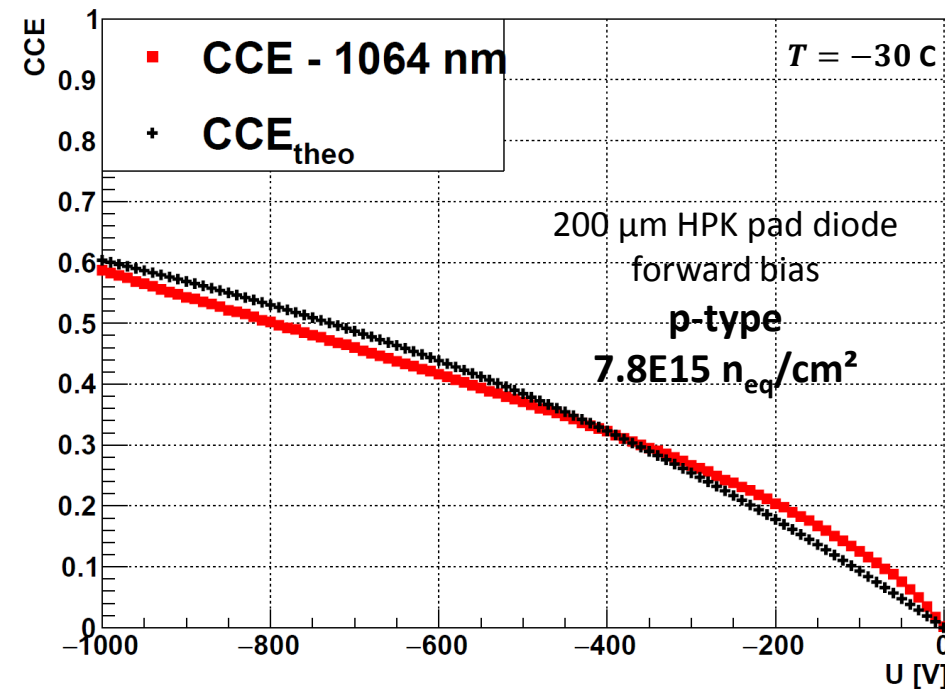
$$\rightarrow \lambda_{e,h}(E, \Phi) = \frac{E}{c_{ccl} \cdot \Phi} \longrightarrow$$

preliminary results:

$$c_{ccl,e} = 6.47E-10 \text{ V}$$

$$c_{ccl,h} = 1.03E-9 \text{ V}$$

# CCE for pad diode

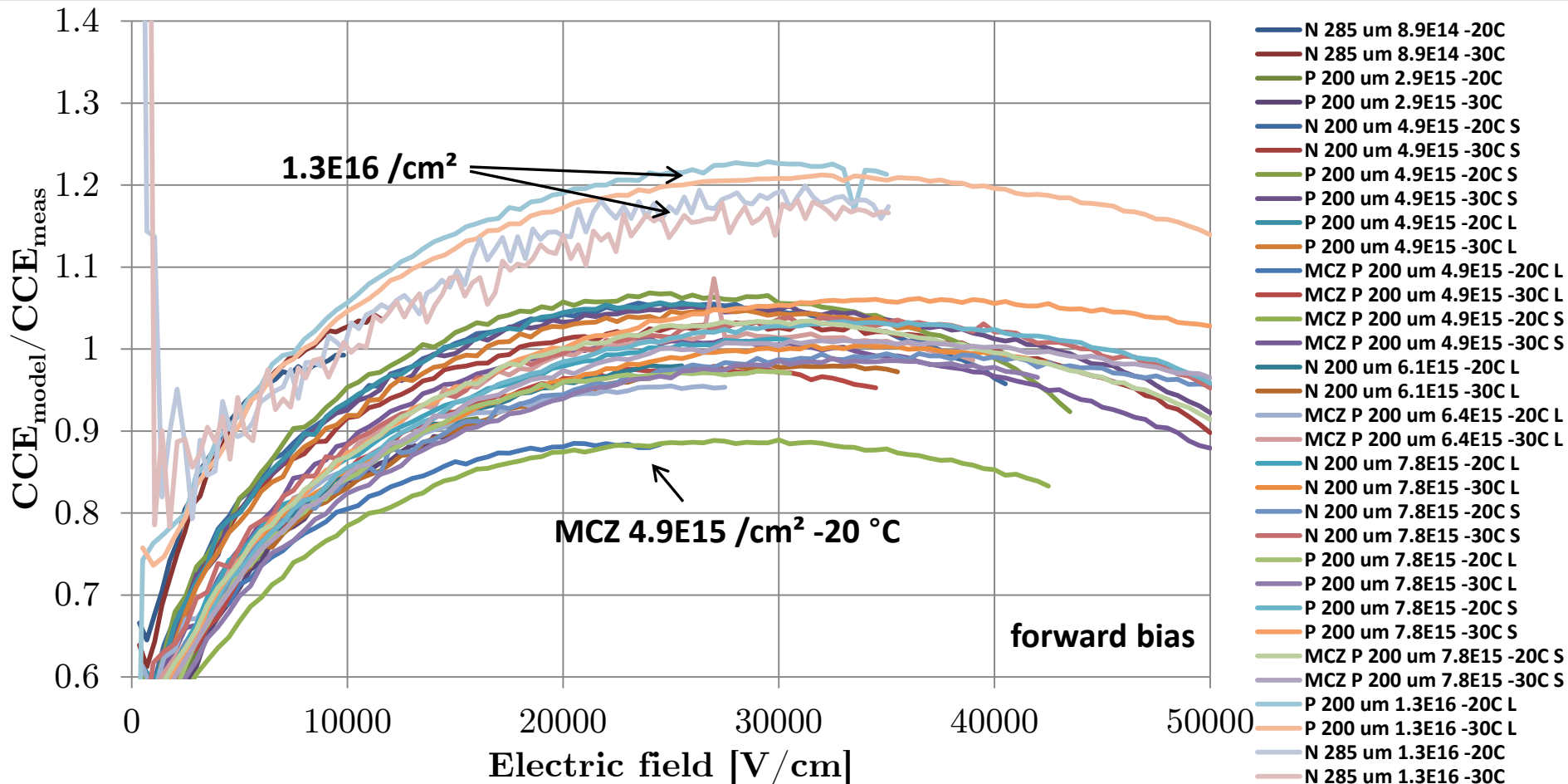


With measured  $\alpha(\Phi, \lambda, T)$  and  $\lambda_{e,h}(E, \Phi) \rightarrow$  predict CCE for pad diodes

- Many different fluences and materials available
- Large pad implant  $\rightarrow$  homogenous e-field near junction, no surface oxide effects

$\rightarrow$  used for cross-check

# CCE for pad diode



Measurement and model w/ CCL from edge TCT agree for high fields but...

- 1.3E16 /cm<sup>2</sup> overestimated + large discrepancy for  $E < 15$  kV/cm





# Conclusion and outlook

# Conclusion and outlook

- Absorption coefficient  $\alpha(\Phi, \lambda, T)$  of near-infrared light determined
  - **Absorption length needed to compare  $CCE_{\text{laser}}$  and  $CCE_{\text{MIP}}$ !**
- Charge collection length determined for forward bias  $\lambda_{e,h}(E, \Phi)$  from edge-TCT
  - Cross-checked with diode TCT

**Simple model with 3 parameters predicts forward CCE for wide range of fluences, electric fields, and independent of material**

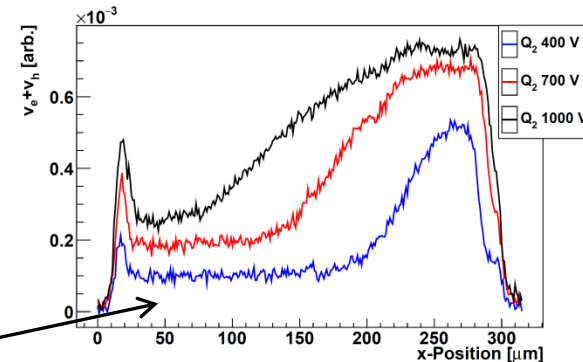
# Conclusion and outlook

- Absorption coefficient  $\alpha(\Phi, \lambda, T)$  of near-infrared light determined
  - **Absorption length needed to compare  $CCE_{\text{laser}}$  and  $CCE_{\text{MIP}}$ !**
- Charge collection length determined for forward bias  $\lambda_{e,h}(E, \Phi)$  from edge-TCT
  - Cross-checked with diode TCT

**Simple model with 3 parameters predicts forward CCE for wide range of fluences, electric fields, and independent of material**

- **Agenda:**
  - Fit drift velocity to transients  $I(t) \propto q \cdot v \cdot e^{-vt/\lambda}$

$$\rightarrow v_{e,h}(E, \Phi) \text{ and } \tau_{e,h}(E, \Phi) = \frac{\lambda_{e,h}}{v_{e,h}}$$

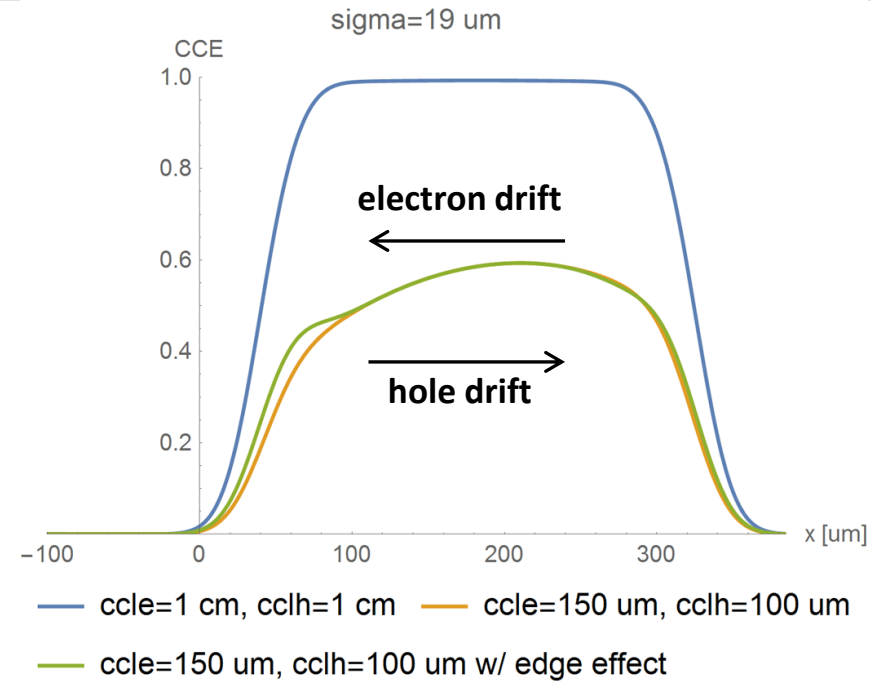
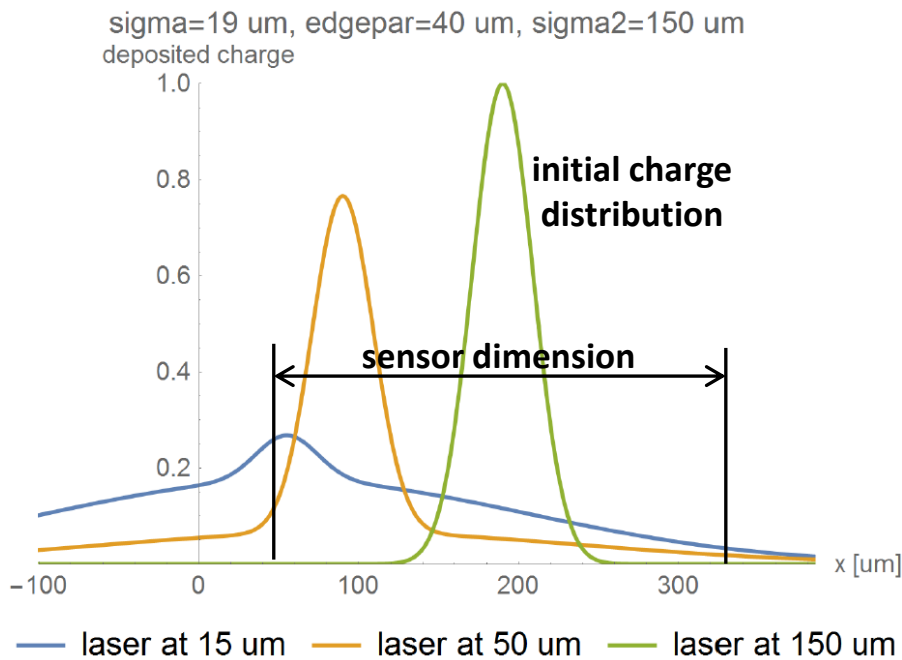


**$\rightarrow$  Apply results for the low field region under reverse bias**



# Backup

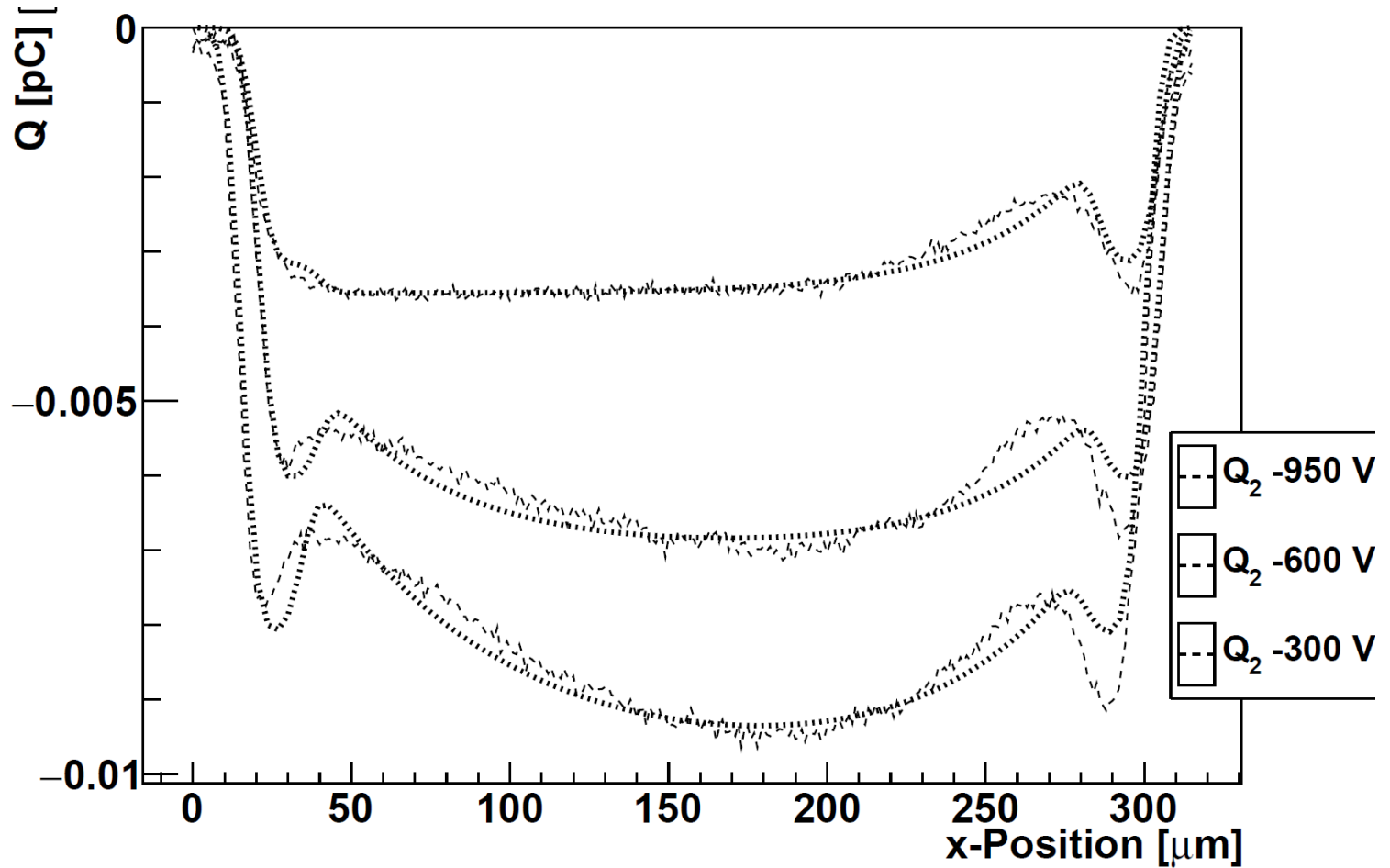
# Fit of the charge profile



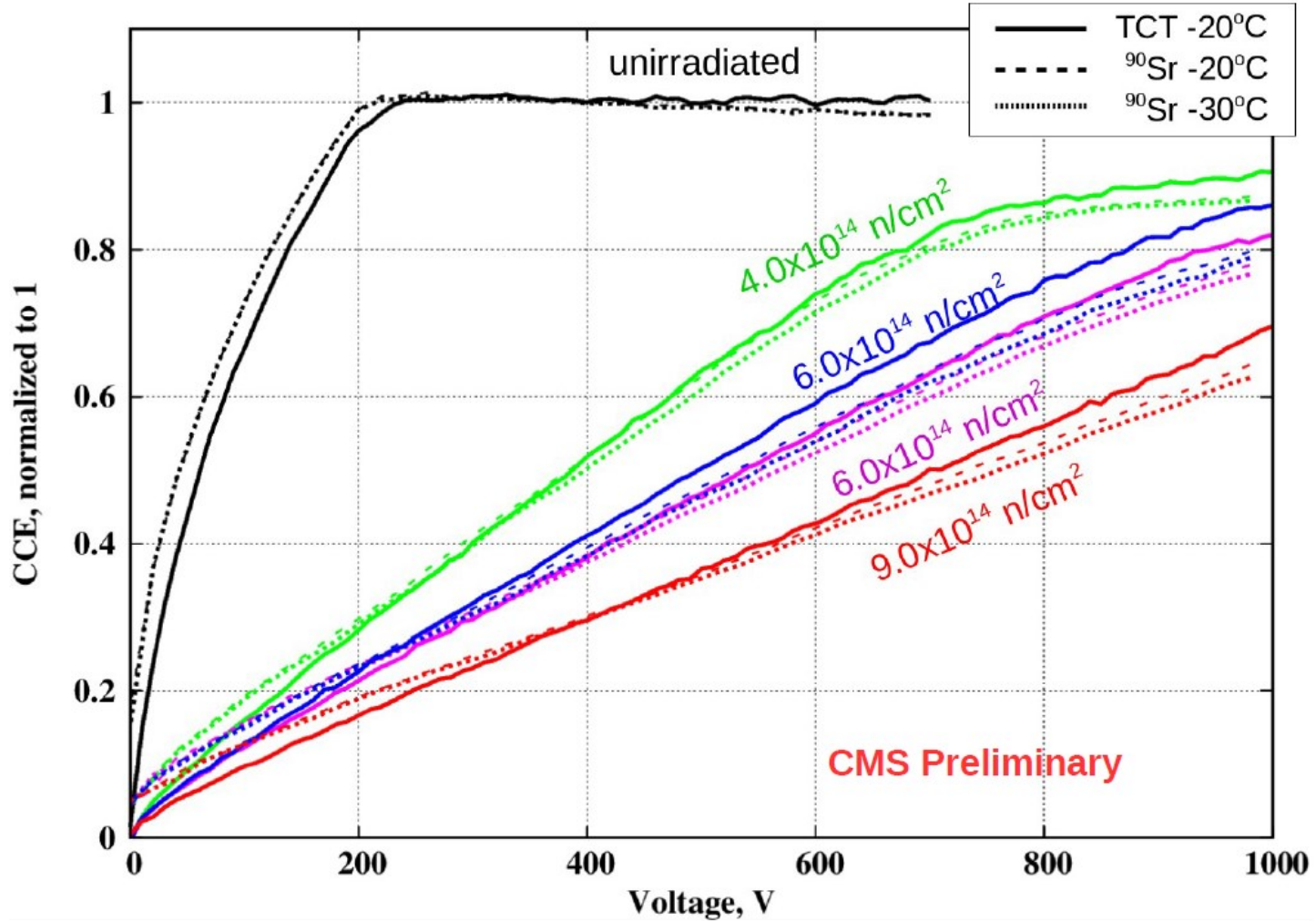
At the corners rounding of the edge and internal reflections modify the initial charge distribution (affects the velocity profile)

- introduce edge parameter
- fit charge collection length to measurements

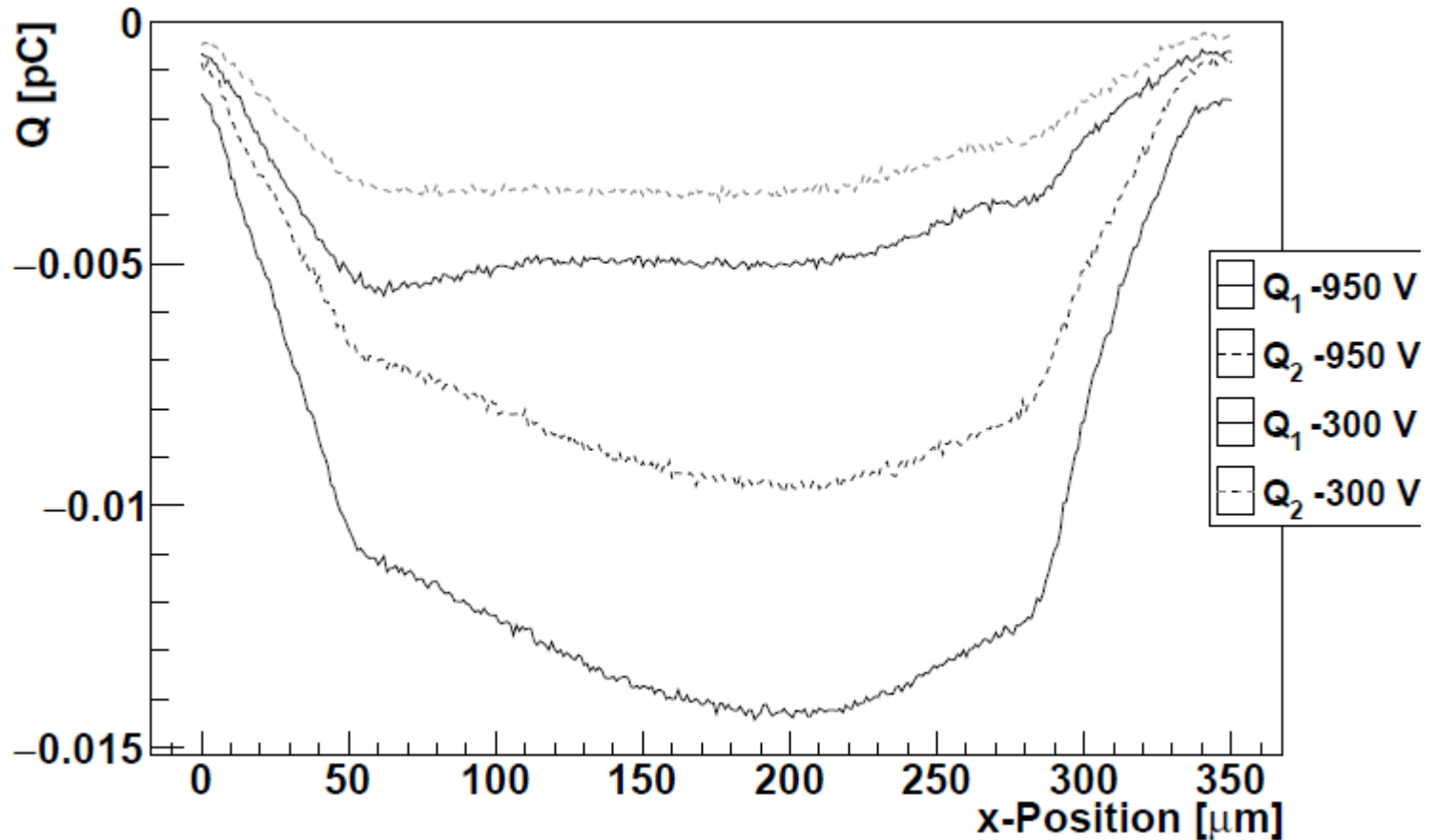
# Charge profile



# CCE pad diodes TCT vs. MIP



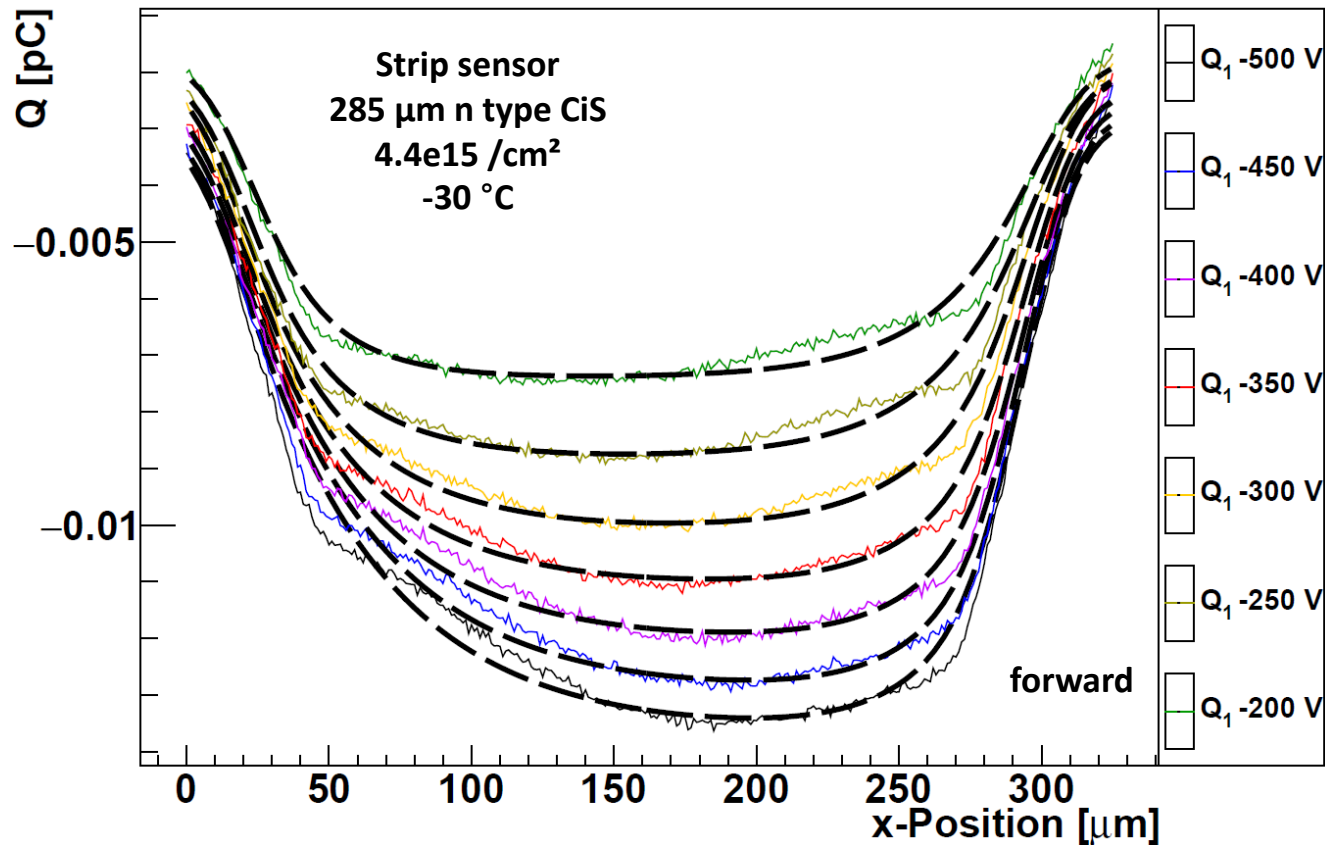
# Charge profile



Strip sensor  
 285 μm n type SiS  
 7.25e15 /cm<sup>2</sup>  
 -30 °C

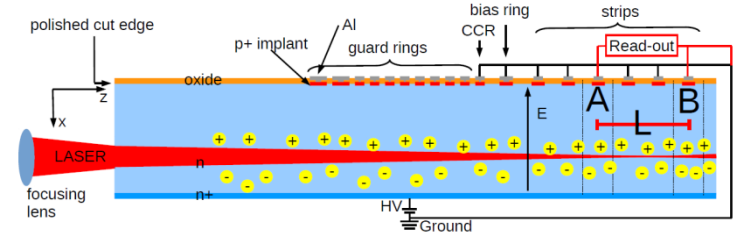
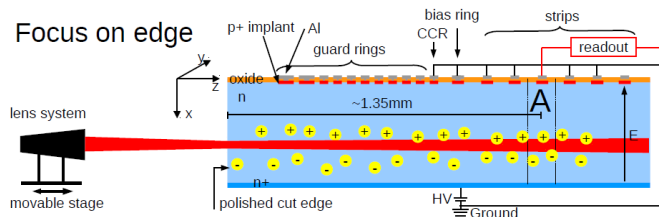
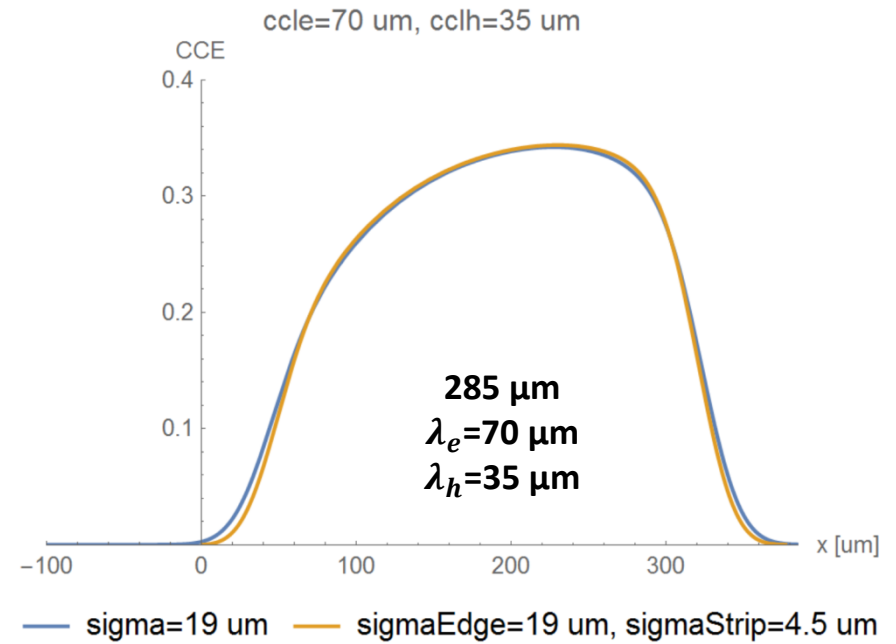
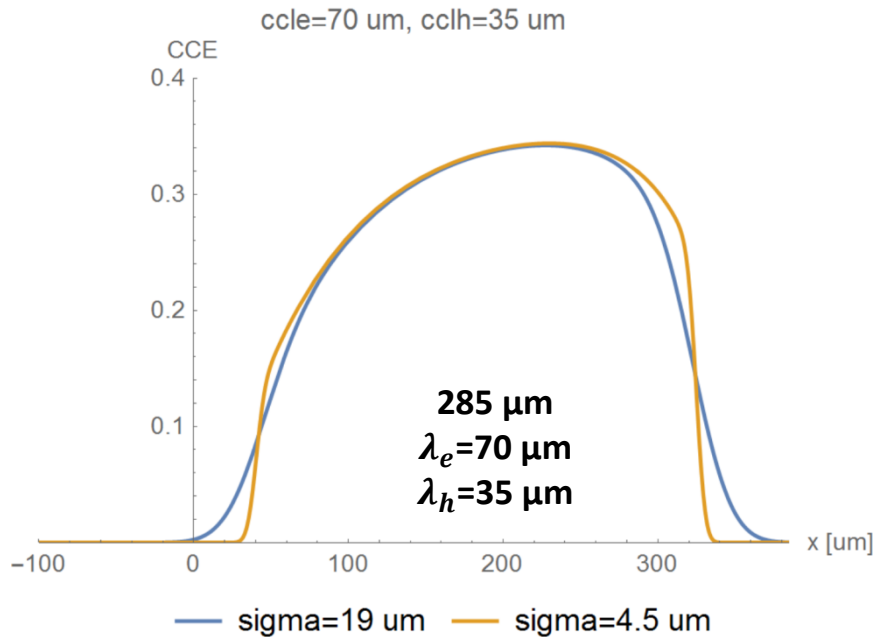


# Fit of the charge profile



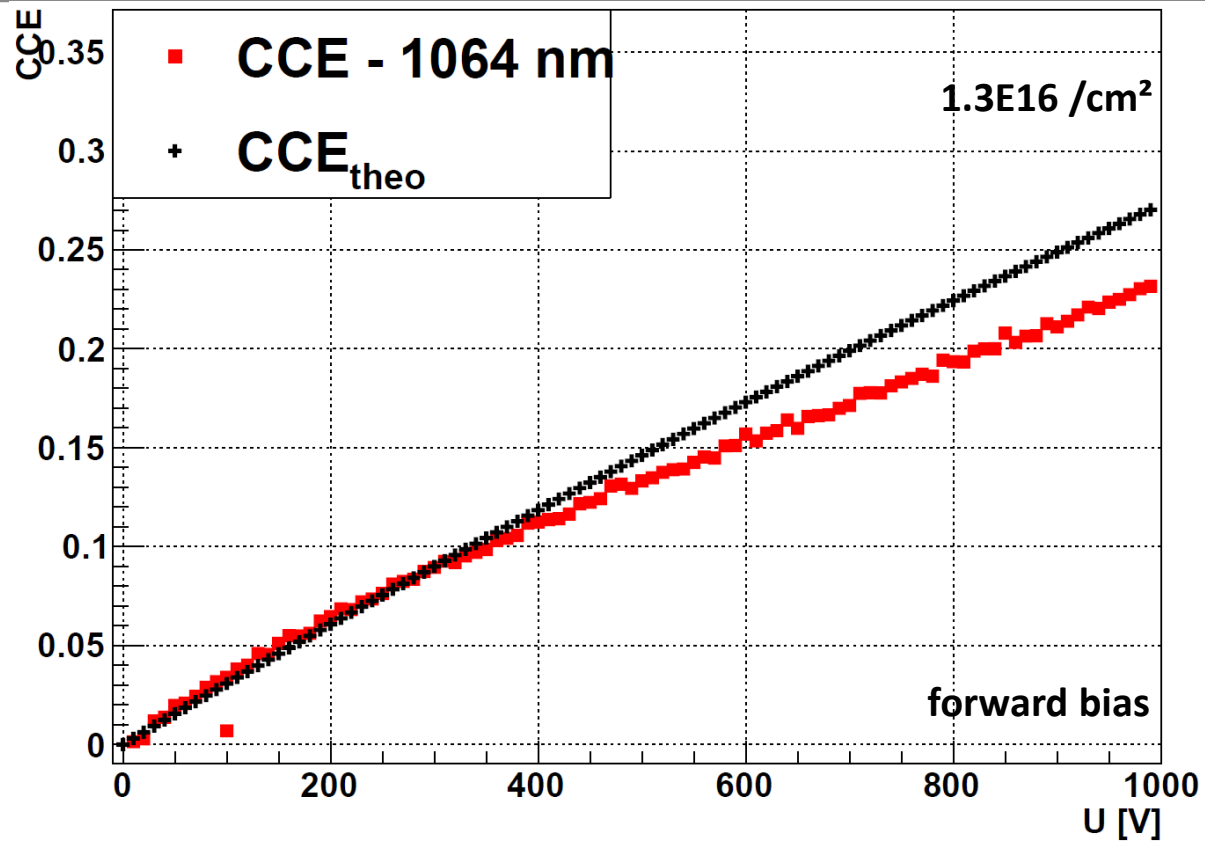
- Obtaining  $\lambda_{e,h}$  by fitting the  $CCE(x)$  seems to work  
→ measurements + analysis ongoing for -20 C and -30 C @ fluences 1E15 – 1.3E16 /cm<sup>2</sup> and for two read out strips

# Fit of the charge profile



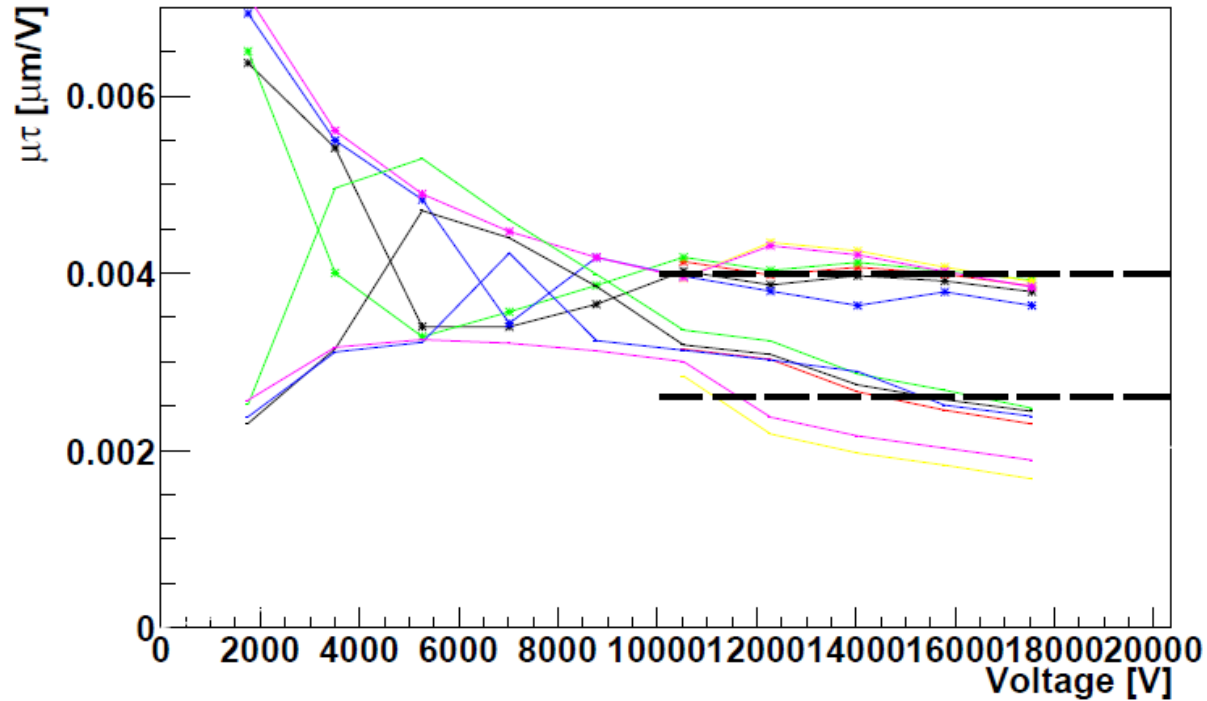
- Better to put the focus @ the edge of the sensor??  
 → most measurements w/ focus between read out strips...

# CCE for pad diode



- 1.3E16 /cm<sup>2</sup> overestimated

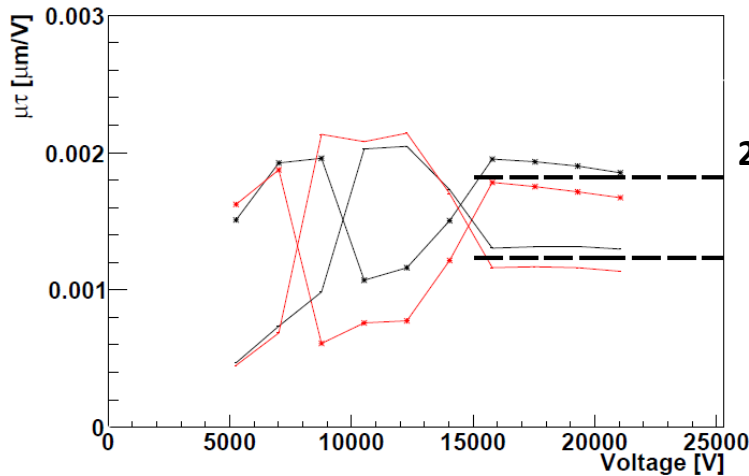
# The charge collection length



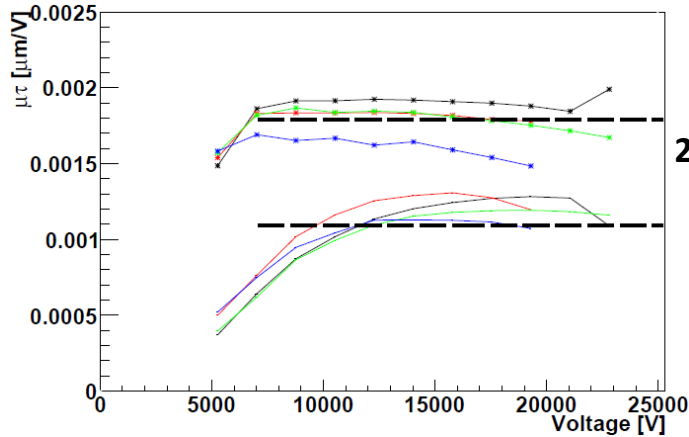
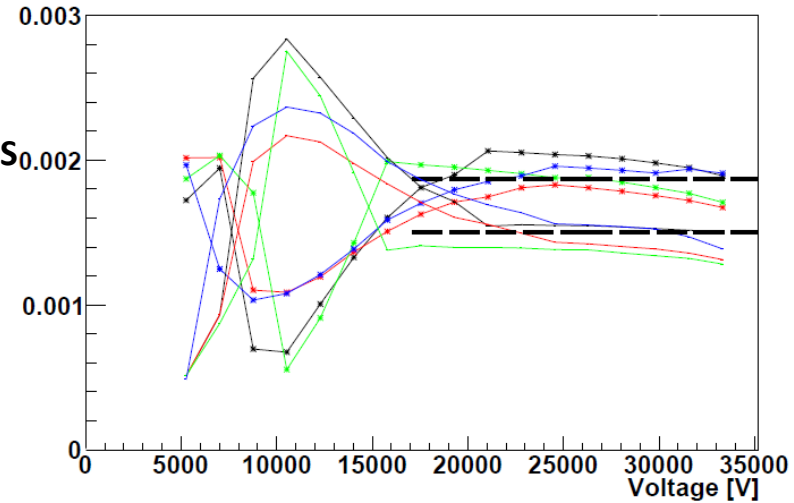
Strip sensor  
 285  $\mu\text{m}$  n type  $\text{CiS}$   
 -20 °C  
 4.4e15 / $\text{cm}^2$   
 forward

$$\mu(E) = \frac{e \cdot \tau_{scatter}(E)}{m}$$

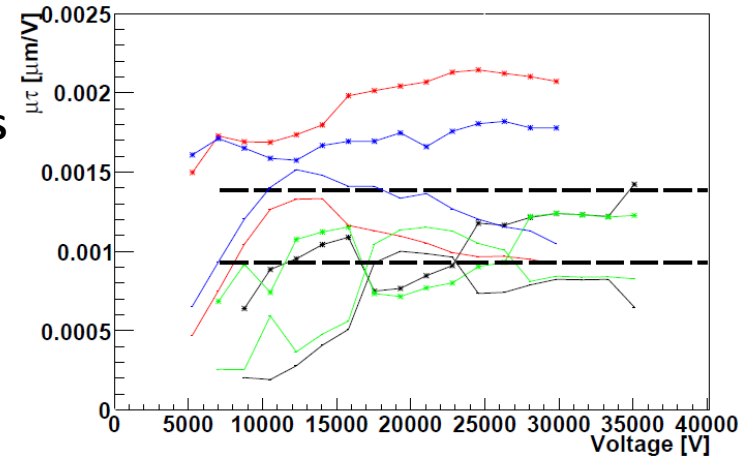
# The charge collection length



Strip sensor  
285 μm n type CiS  
-20 °C & -30 °C  
7.3e15 /cm<sup>2</sup>  
forward

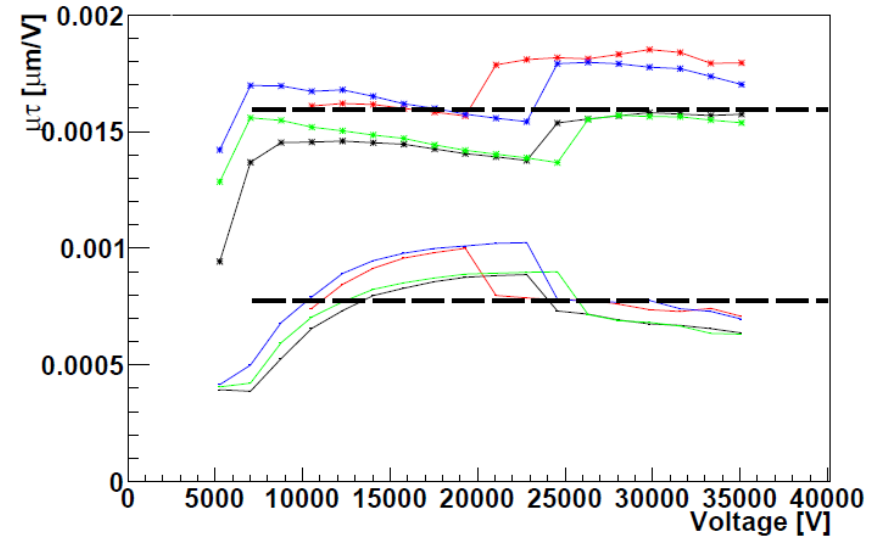
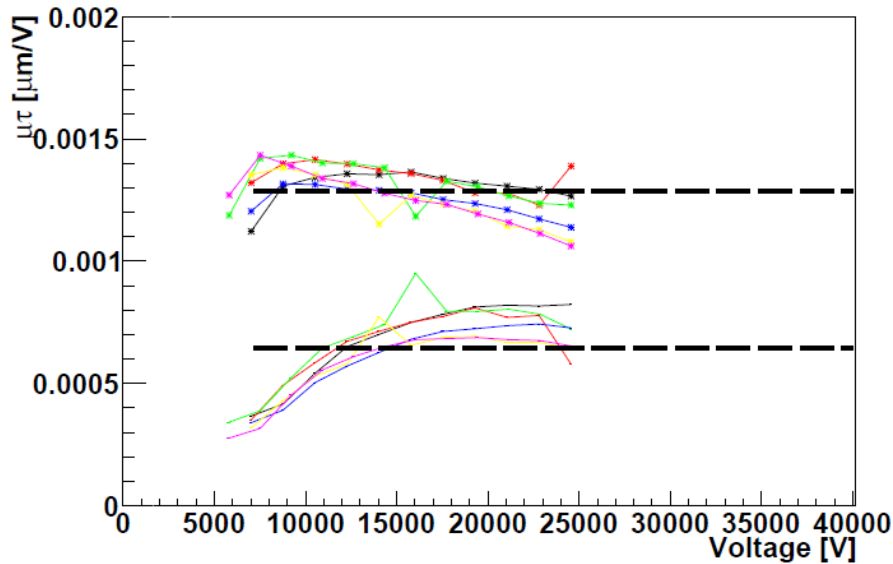


Strip sensor  
285 μm n type CiS  
-20 °C & -30 °C  
9.4e15 /cm<sup>2</sup>  
forward



- $\lambda_{e,h} = v\tau = \mu E\tau \approx \text{const} \cdot E$

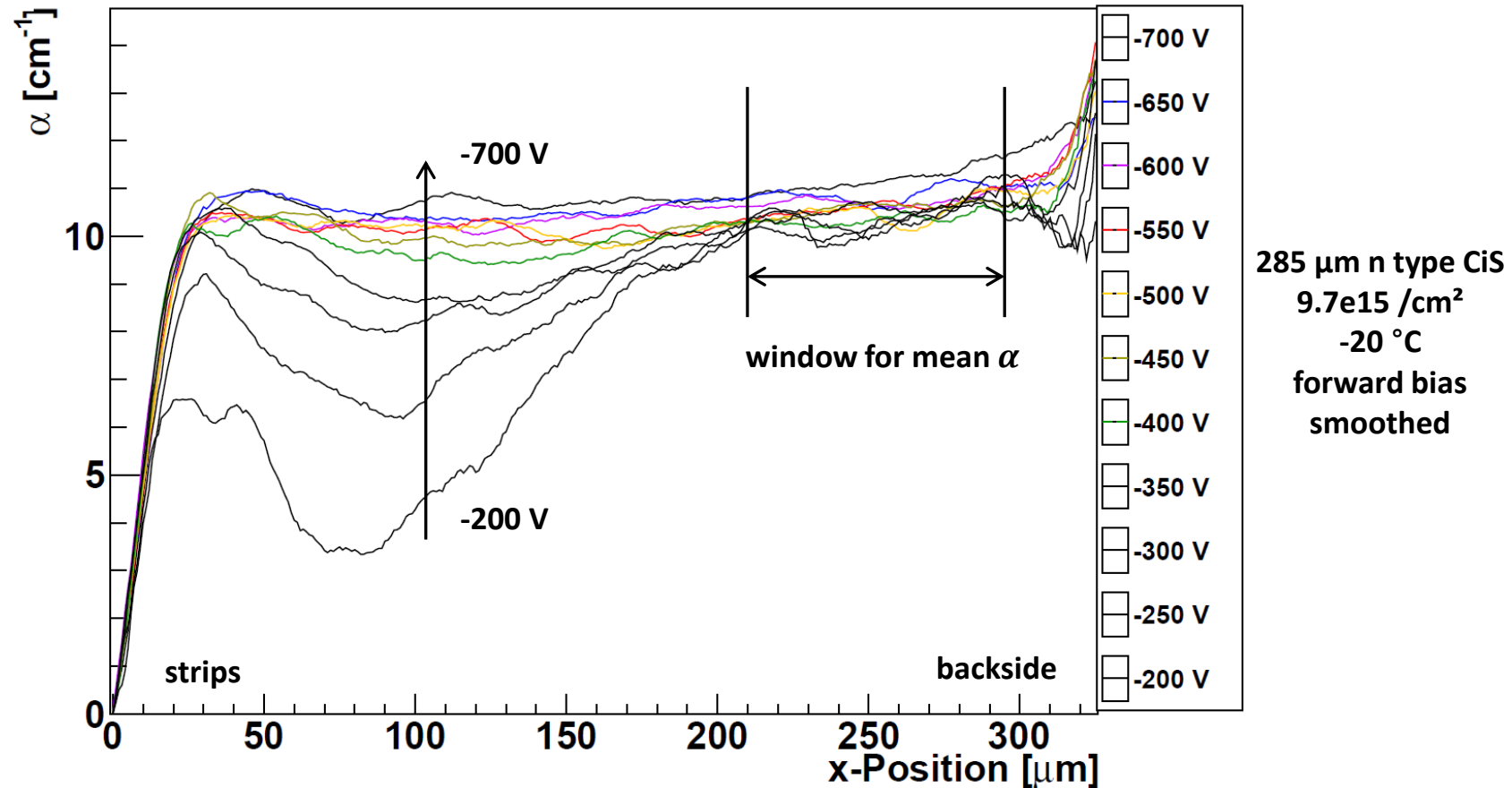
# The charge collection length



Strip sensor  
 285 μm n type CiS  
 -20 °C & -30 °C  
 1.3e16 /cm<sup>2</sup>  
 forward

- $\lambda_{e,h} = v\tau = \mu\tau E \approx \text{const} \cdot E$

# Absorption from edge TCT



- Absorption coefficient depends on voltage and position in the sensor  
 → investigate absorption away from strips where E-field homogeneous

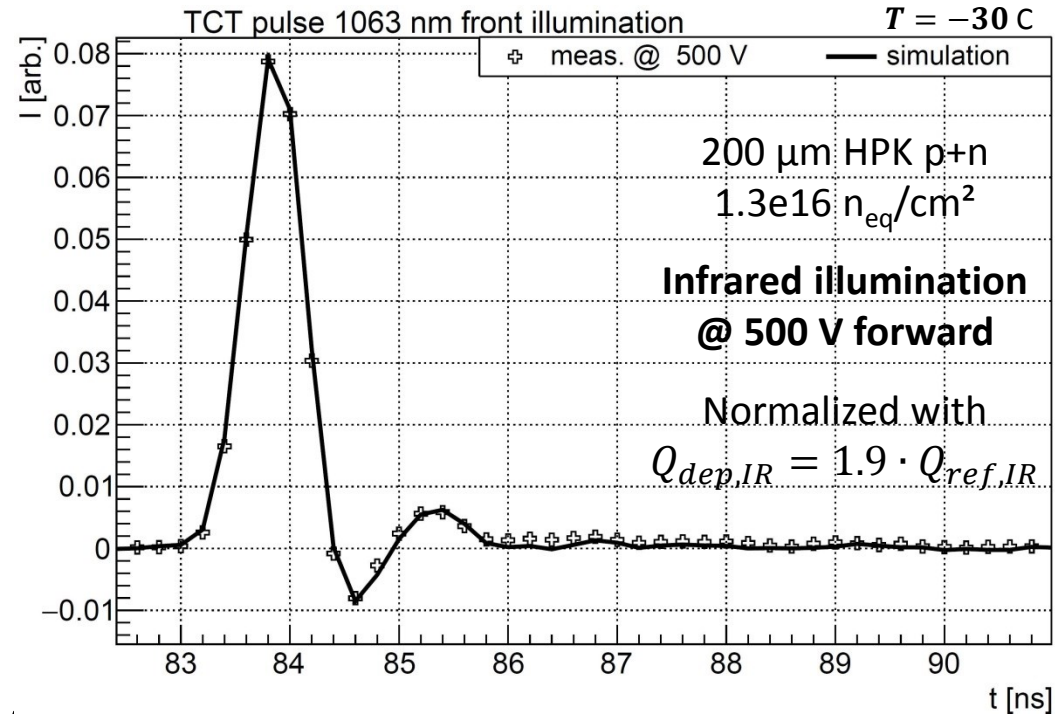
# Drift velocity and trapping

## Next step:

- Disentangle drift velocity and trapping:

$$I(t) \propto q \cdot v \cdot e^{-vt/\lambda}$$

- Fit the drift velocity  $v$  to transients with  $\lambda_{e,h}$  from CCE
- Extract  $\tau_{e,h} = \lambda/v$

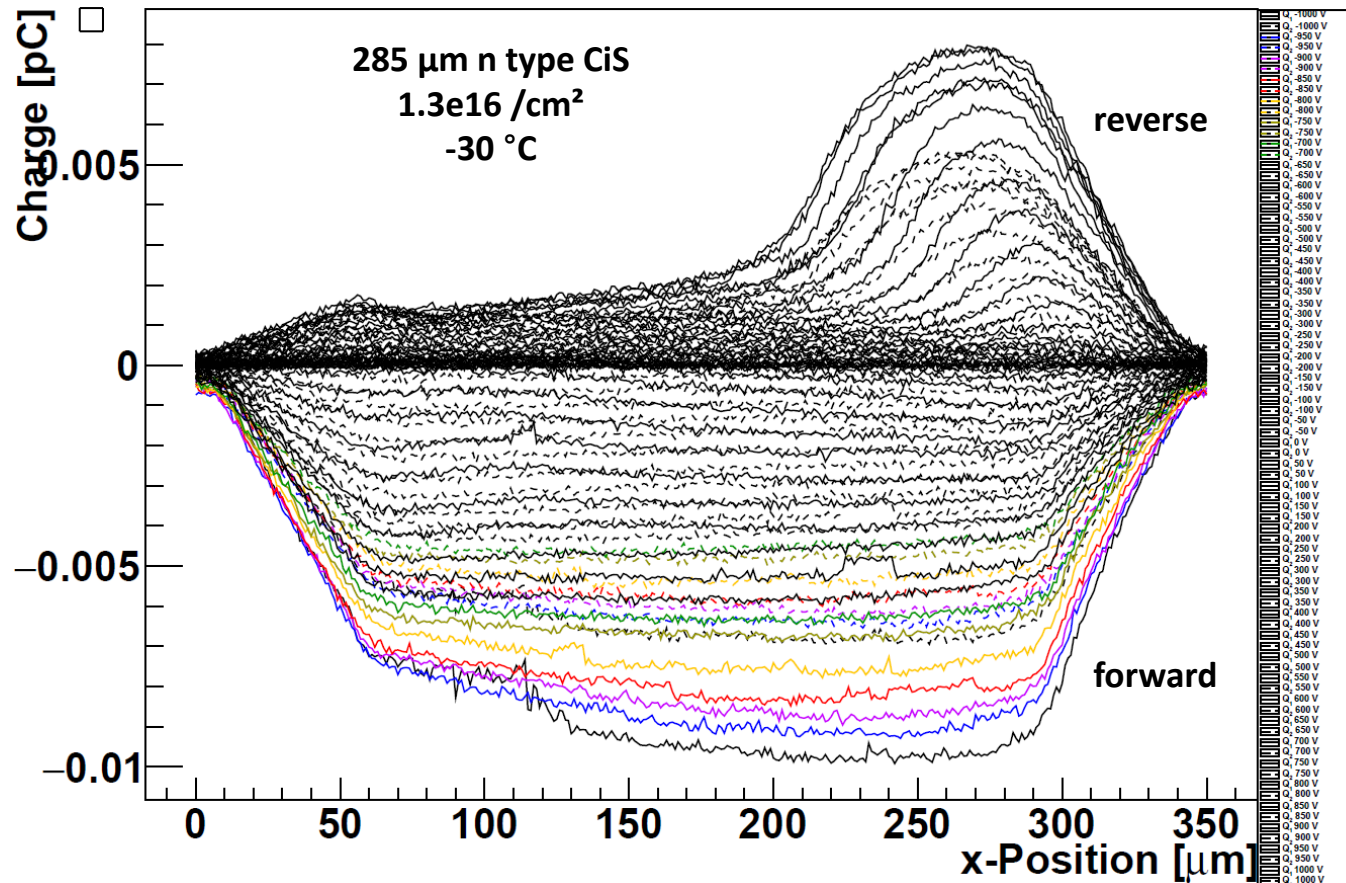


Simulation fits nicely (here  $E = 25\text{ kV/cm}$ )

- $v$  reduced by 35 % compared to non irradiated
  - Expected  $v$  reduction for  $\sim 10^{16} / \text{cm}^3$  ionized impurities
- Carrier lifetimes for  $1.3 \times 10^{16} n_{\text{eq}}/\text{cm}^2$ :
  - $\tau_e = 400\text{ ps}$
  - $\tau_h = 140\text{ ps}$



# Edge-TCT charge profile



- Collected charge measured at different depth (x-position) in strip sensor  
 → read out two strips and determine absorption @ 1052 nm